MARCH AP-1500 Plasma System

Extra-Large Plasma Chamber for Efficient Batch Processing

The AP-1500™ plasma system is designed to provide large-volume plasma treatment for batch applications. The space-efficient design is ideal for treating all types of parts and components, and mulitple systems can be placed side-by-side to maximize the use of floor space.

The AP-1500 system provides:

- Simple system operation and data logging
- A compact enclosure that contains the pump, chamber, control electronics, and 40 KHz RF generator
- Slide-out horizontal shelves for easy load and unload
- Advanced power matching and control system algorithms for maximum efficiency
- An intuitive touch-screen control panel for real-time process monitoring
- Low daily operating expenses, such as process gases and power consumption
- Multi-level control-system password protection to prevent unauthorized recipe modification
- Front and rear maintenance doors for convenient access to all interior components and the pump is positioned on rollers for easy removal

Key Applications

- Plasma cleaning
- Surface activation
- Adhesion improvement

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Specifications

Enclosure Dimensions	W x D x H – Footprint	1118W x 1196D x 2407H mm (44W x 47D x 95H in.)
	Net Weight	921 kg (2030 lbs.)
	Equipment Clearance	Right, Left – 153 mm (6 in.), Front – 680 mm (27 in) Back – 483 mm (19 in.) min.
Chamber	Maximum Volume	442.4 liters (27,000 in^3)
	Variable Electrode Configurations	Power-Ground, Ground-Power, Power-Power
	Number of Electrode Positions	14
	Electrode Pitch	50.8 mm (2 in.)
Electrodes	Powered Working Area	643W x 641D mm (25.3W x 25.2D in.)
	Ground/Perforated Working Area	698W x 641D mm (27.5W x 25.2D in.)
	Floating Working Area	643W x 641D mm (25.3W x 25.2D in.)
RF Power	Standard Wattage	2000 W
	Frequency	40 KHz
Gas Control	Available Flow Volumes	10, 25, 50, 100, 250, 500, 1000, 2000 or 5000 sccm
	Maximum Number of MFCs	4
Control System and Interface	Software Control	PLC Control with Touch Screen Interface
	Remote Interface	PlasmaLINK, ProcessLINK
Vacuum Pump	Standard Wet Pump	53 cfm with Oxygen Oil Mist Eliminator
	Optional Wet Pump	53 cfm with Corrosive Oil Mist Eliminator
	Optional Purged Dry Pump	63 cfm
	N2 Purged Pump Flow	14 slm
	Cooling Water Purged Pump Flow	5 slm
Facilities	Power Supply	220 V, 25 A, 50/60 Hz, 3-Phase, 8 AWG, 4-Wire 380 V, 25 A, 50/60 Hz, 3-Pahse, 8 AWG, 5-Wire
	Process Gas Fitting Size & Type	6.35 mm (0.25 in.) OD Swagelok Tube
	Process Gas Purity	Lab or Electronic Grade
	Process Gas Pressure	0.69 bar (10 psig) min. to 1.03 bar (15 psig) max., regulated
	Purge Gas Fitting Size & Type	6.35 mm (0.25 in.) OD Swagelok Tube
	Purge Gas Purity	Lab or Electronic Grade N2/CDA
	Purge Gas Pressure	2 bar (30 psig) min. to 6.9 bar (100 psig) max., regulated
	Pneumatic Valves Fitting Size & Type	6.35 mm (0.25 in.) OD Swagelok Tube
	Pneumatic Gas Purity	CDA, Oil Free, Dewpoint ≤7°C (45°F), Particulate Size <5 µm
	Pneumatic Gas Pressure	3.45 bar (50 psig) min. to 6.89 bar (100 psig) max., regulated
	Exhaust	38 mm (1.5 in.) OD Pipe Flange
Compliance	SEMI	S2/S8 (EH&S/Ergonomics)
	International	CE Marked
Ancillary Equipment	Gas Generators	Nitrogen, Hydrogen (Requires Additional Non-Optional Hardware)
	Facilities	Chiller, Scrubber

For more information, speak with your Nordson representative or contact your Nordson regional office.

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MARCH Products
2470-A Bates Avenue
Concord, CA 94520-1294, U.S.A
info@nordsonmarch.com

+1.925.827.1240
nordsonmarch.com

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